

U.S. Department of Commerce, Patent and Trademark Office  INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Application No.:	Unknown
	Filing Date:	January 13, 2004
	First Named Inventor:	Chunsheng Huang
	Group Art Unit:	Unknown
	Examiner Name:	Unknown
	Confirmation No.:	Unknown
	Attorney Docket No.:	NAN064 US

## U.S. Patent Documents

*Examiner Initials		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
	1.	US 2003/0020912	01-2003	Norton et al.	356	369	
	2.	US -4,298,283	11-1981	Makosch et al.	356	495	
	3.	US 4,583,855	04-1986	Baraket, Noah	356	491	
	4.	US 4,859,017	08-1989	Brierley et al.	385	27	
	5.	US 4,872,755	10-1989	Kuchel, Michael	356	495	
	6.	US 5,392,116	Feb. 21, 1995	Makosch	356	351	
	7.	US 5,502,567	Mar. 26, 1996	Pokrowsky	356	367	
	8.	US 5,561,525	10-1996	Toyonga et al.	356	512	
	9.	US 5,889,593	Mar. 30, 1999	Bareket	356	445	
	10.	US 6,052,188	04-2000	Fluckiger et al.	356	369	
	11.	US 6,201,609	03-2001	Hill et al.	356	491	
	12.	US 6,275,291	Aug. 14, 2001	Abraham et al.	356	367	
	13.	US 6,304,330	10-2001	Millerd et al.	356	521	
	14.	US 6,452,682	09-2002	Hill et al.	356	493	
	15.	US 6,515,745	02-2003	Vurens et al.	356	369	

## Foreign Patent Documents

							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	16.	EP 0 987 537 A2	Mar. 22, 2000	Europe				x
	17.	WO 02/15238 A2	Feb. 21, 2002	PCT	H01L	21/00		
	18.	WO 02/16893 A2	Feb. 28, 2002	PCT	G01J			

## Other Art (Including Author, Title, Date, Pertinent Pages, Etc.)

	19.	Azzam, R.M.A. et al., <i>Ellipsometry and Polarized Light</i> , Chapter 3, "Theory and Analysis of Measurements in Ellipsometer Systems" (1987) Pages 167-268.
	20.	Azzram, R., "An arrangement of two reflective photodetectors for measuring all four Strikes parameters of

Examiner:

Date Considered:

\* Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication with applicant.

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		light", <i>American Institute of Physics</i> (1991) Pages 2080-2082
	21.	Bennett, J., "Polarizers", Chapter 3, <i>Handbook of Optics</i> , (1995) Pages 3.1-.3.70
	22.	Cumming, D. et al., "A variable polarization compensator using artificial dielectrics" Elsevier Science (1999) Pages 164-168
	23.	Hauge, P., "Recent Developments in Instrumentation in Ellipsometry", <i>Surface Science</i> 96 (1980) Pages 108-140.
	24.	Horn, T., "Liquid Crystal Imaging Stokes Polarimeter", <i>Astronomical Society of the Pacific</i> (1999) Pages 33-37.
	25.	Jaspersen, S., "A Modulated Ellipsometer for Studying Thin Film Optical Properties and Surface Dynamics" <i>Surface Science</i> 37 (1973) Pages 548-558.
	26.	Kazam, A. et al., "Compact and high-speed ellipsometer" <i>SPIE</i> Vol. 1681 Pages (1992) 183-188.
	27.	Lee, J. et al., "Rotating-compensator multichannel ellipsometry: Applications for real time Stokes vector spectroscopy of thin film growth", <i>Review of Scientific Instruments</i> 69 (1998) Pages 1800-1810.
	28.	Oliva, E., "Wedge double Wollaston, a device for single shot polarimetric measurements", <i>Astronomy &amp; astrophysics Supplement Series</i> 123 (1997) Pates 589-592.
	29.	Smajkiewicz, A., "An Argument for a Filter Array vs. Linear variable Filter in Precision Analytical Instrument Applications", Document #P95081
	30.	"Stokes Polarimetry Using Liquid-Crystal Variable Retarders", downloaded 6/11/01 from <a href="http://www.meadowlark.com/AppNotes/appnote3.htm">http://www.meadowlark.com/AppNotes/appnote3.htm</a> , Meadowlark Optics, Inc. (1998-2001).

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